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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Katsuhiko MIYA et al.

Serial No.: 10/648,918

Filed: August 27, 2003

New York, New York

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For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING
METHOD DRYING SUBSTRATE

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Sir:

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Enclosures



APPLICANT'S ART CITATION (Include copy of this form with next communication to the applicant)	Application 10/648,918	OFGS File No. P/1250-258
	Applicant Katsuhiko MIYA et al.	
	Filing Date August 27, 2003	Group Art Unit

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	Filing Date If Appropriate
	US- 2002/0074020 A1	06/2002	Ono et al.			08/29/2001
	US-					
	US-					
	US-					
	US-					
	US-					
	US-					
	US-					
	US-					

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM-YYYY	Country	Class	Sub-class	Translation	
						Yes	No
	11-274135	10-1999	Japan				X
	2002-176026	06-2001	Japan			X	
	11-176795	07-1999	Japan				X

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	English translation of Abstract for Japanese Patent Application Laid Open No. 11-274135
	English translation of Abstract for Japanese Patent Laid Open No. 11-176795
	Japanese Patent Application Laid Open No. 2002-176026 which is the counterpart
	to U.S. Patent Application Publication No. 2002/0074020 A1 (as listed above)

Examiner	Date Considered
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.